



6-13-2015

Thickness Measurement on Ti, Au, Pd, and Cr using PVD75 E-beam Evaporator

Dhruv Turakhia
tdhruv@seas.upenn.edu

Follow this and additional works at: https://repository.upenn.edu/scn_tooldata

Turakhia, Dhruv, "Thickness Measurement on Ti, Au, Pd, and Cr using PVD75 E-beam Evaporator", *Tool Data*. Paper 30.
https://repository.upenn.edu/scn_tooldata/30

This paper is posted at ScholarlyCommons. https://repository.upenn.edu/scn_tooldata/30
For more information, please contact repository@pobox.upenn.edu.

Thickness Measurement on Ti, Au, Pd, and Cr using PVD75 E-beam Evaporator

Keywords

Thickness, Ti, Au, Pd, Cr

Creative Commons License



This work is licensed under a [Creative Commons Attribution-Share Alike 4.0 International License](https://creativecommons.org/licenses/by-sa/4.0/).

Thickness Measurement on Ti, Au, Pd, and Au using PVD75 E-beam Evaporator (Graduate Student Fellow Program)

Prepared by Dhruv Turakhia (6/5/2015)

Deposition Rate: 2 Å/sec

Final Thickness Set Point: 300 nm

Default Tooling Factor Xtal 1: 54

Default Tooling Factor Xtal 2: 100

Thickness measurement: P7 Stylus Profiler

Ti deposition

Measured thickness: 306.0 ± 9.6 nm

Au deposition

Measured thickness: 237.6 ± 4.2 nm

Pd deposition

Measured thickness: 265.5 ± 17.8 nm

Cr deposition

Measured thickness: 407.2 ± 16.5 nm